k-Space Associates, Inc.



No. 10 Summer 2006

100km Radius of Curvature Resolution Achieved with kSA MOS in France!

Within a few hours of installing a kSA MOS on a UHV evaporation system at the *Laboratoire de Thermodynamique et Physico-Chimie Métallurgiques* (LTPCM), we demonstrated a

radius of curvature resolution of over 100km! Dr. Bruno Gilles and Dr. Marc Verdier are using the kSA MOS to investigate thin film stress in a variety of material systems. With over a hundred



units in the field, the kSA MOS is the highest resolution 2D curvature and stress sensor available today.

Tech Tips: Custom Data Exporting for all kSA Products

Thanks to your suggestions, we have created a custom data export capability for all kSA products. It allows you to set up exactly what data you want to export, and then save that custom export configuration for the future. You also can save multiple configuration files, allowing you to load the configuration file you want for your custom data export. As always with kSA software, auto-save and auto-export data to Excel, *.kdt (k-Space data file format), or standard text file.

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Measure SiC Substrate Temperature with kSA BandiT!

Recently developed spectra-processing techniques at k-Space now enable accurate and reproducible temperature monitoring of 4H and 6H SiC during MOCVD growth, demonstrated from 200-1250°C. The signal is particularly strong with those MOCVD systems using graphite or SiC-coated graphite susceptors because they provide excellent light scattering and a source of diffuse light required for kSA BandiT temperature



monitoring. Look for a new Application Note soon with more details, or contact kSA today.

Multi-Wafer Sorting Software Now Available!

All kSA products now have the ability to provide spatially resolved and wafer-sorted information during multi-wafer deposition. By placing markers at various radial locations around the platen or susceptor, this data can be acquired in real time.



The figure above shows user-selected vertical markers placed at center-wafer locations on a five-wafer platen. The valleys in the data between each wafer is the platen.

Come see k-Space at the following upcoming conferences:

- 14th International MBE Conference Tokyo, Japan September 3-8th
- Vacuum 2006 Tokyo, Japan September 13-15th
- 24th North American Conference on Molecular Beam Epitaxy Durham, NC October 8-11th, 2006

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